

Attorney's Docket No.: 07977-270001 / US4820

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant : Yonezawa, et al. Art Unit : 1763
Serial No.: 09/820,520 Examiner : Luz L. Alejandro
Filed : March 28, 2001 Confirmation No. : 5433
Title : PLASMA CVD DEVICE AND DISCHARGE ELECTRODE

Commissioner for Patents
Washington, D.C. 20231

AMENDMENT

Sir:

In response to the Official Action dated August 7, 2002,
Paper No. 5, in the above-referenced application, please amend
the above-identified application as follows.

In the Claims:

Please amend claim 1 as follows:

1. (Amended) A plasma CVD apparatus comprising:
a vacuum chamber;
an introducing means for introducing a gas into the vacuum
chamber;
an exhaust means for exhausting the gas from the vacuum
chamber to an outside;

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November 7, 2002

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